	Application No.	Applicant(s)		
	10/050,426	NUTTALL ET AL.	NUITTALL ET AL	
Notice of Allowability	Examiner	Art Unit		
	Jack Chen	2813	AW	
The MAILING DATE of this communication app All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85 NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT R of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in the commetter of the comme	n this application. If not include unication will be mailed in due	ed course. <b>THIS</b>	
1. $\boxtimes$ This communication is responsive to $\underline{2/10/04}$ .				
2. The allowed claim(s) is/are 60-76.				
3. $\boxtimes$ The drawings filed on <u>10 October 2003</u> are accepted by the	ne Examiner.			
<ul> <li>4. Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). <ul> <li>a)   All   b)   Some*   c)   None   of the:</li> <li>1.   Certified copies of the priority documents have been received.</li> <li>2.   Certified copies of the priority documents have been received in Application No</li> <li>3.   Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).</li> <li>* Certified copies not received:</li> </ul> </li> <li>Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.  THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.</li> <li>5.   A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.</li> <li>6.   CORRECTED DRAWINGS ( as "replacement sheets") must be submitted.  (a)   including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached  1)   hereto or 2)   to Paper No //Mail Date  (b)   including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No //Mail Date  Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).</li> <li>7.   DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.</li> </ul>				
Attachment(s)  1. Notice of References Cited (PTO-892)  2. Notice of Draftperson's Patent Drawing Review (PTO-948)  3. Information Disclosure Statements (PTO-1449 or PTO/SB/Paper No./Mail Date  4. Examiner's Comment Regarding Requirement for Deposit of Biological Material	6. ☐ Interview S Paper No. 08), 7. ☑ Examiner's	 Jack Chen	·	
		Primary Examiner Art Unit: 2813		

## **DETAILED ACTION**

In response to the communication filed on February 10, 2004, claims 60-76 are active in this application.

## **EXAMINER'S AMENDMENT**

1. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Mark S. Matkin on May 1, 2004.

The application has been amended as follows:

Re claim 60, line 7, insert –, the substrate being provided to comprise exposed substantially amorphous material—after "chemical vapor deposition reactor".

## Reasons For Allowance

- 2. Claims 60-76 are allowable over the prior art of record. The generic claim 60 is allowable; accordingly, the previous species restriction dated on January 12, 2004 is hereby withdrawn.
- The following is an examiner's statement of reasons for allowance: the prior art of record 3. neither teach nor make obvious the method for forming the capacitor by exposing both of the substantially amorphous material and the substantially crystalline capacitor dielectric to the silicon precursor in the CVD reactor under conditions effective to substantially selectively

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deposit polysilicon on the substantially crystalline capacitor dielectric layer and **NOT** on the exposed substantially amorphous material to form the second polysilicoon capacitor electrode.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

## Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Jack Chen whose telephone number is (571)272-1689. The examiner can normally be reached on Monday-Friday (9:00am-6:30pm) alternate Monday off.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Carl W Whitehead can be reached on (571)272-1702. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Jack Chen

Primary Examiner

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